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2000.076000Serial No.
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List of Patents and Publications for Applicant's

Applicant
Richard J. Markle

INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

Filing Date:
June 13, 2001Group:
1765U.S. Patent Documents
See PageForeign Patent Documents
See Page 1Other Art
See Page 1

U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
	A1						

Foreign Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Country	Class	Sub Class	Translation Yes/No
L.T.M.E.	B1	EP1096556A1	05/02/2001	EP			
L.T.M.E.	B2	EP0690483A2	01/03/1996	EP			
L.T.M.E.	B3	WO99/47618	09/23/1999	PCT			
L.T.M.E.	B4	WO98/26025	06/18/1998	PCT			
L.T.M.E.	B5	WO00/00567	01/06/2000	PCT			
L.T.M.E.	B6	WO00/34998	06/15/2000	PCT			
L.T.M.E.	B7	WO98/36045	08/20/1998	PCT			
L.T.M.E.	B8	WO97/03175	01/30/1997	PCT			

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Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
L.T.M.E.	C1	"Modification of the Preston Equation for the Chemical-Mechanical Polishing of Copper" Q. Luo, S. Ramarajan, S.V. Babu; <i>Thin Solid Films</i> 335 (1998) Pages 160-167.
L.T.M.E.	C2	"Initial Study on Copper CMP Slurry Chemistries" Ronald Carpio, Janos Farkas, Rahul Jairath; <i>Thin Solid Films</i> 266 (1995) pages 238-244.
L.T.M.E.	C3	International Search Report for PCT/US02/12829; mailed July 1, 2002.

EXAMINER: Lynette T. Wang-Evans

DATE CONSIDERED: 12/27/2003

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